

# BATCH WAFER ID READER

IDWR150; IDWR200

150MM WAFER HANDLING  
 200MM WAFER HANDLING  
 300MM WAFER HANDLING  
 VACUUM HANDLING SYSTEMS  
 RETICLE HANDLING  
 WAFER CARRIERS  
 CARRIER HANDLES



## DESCRIPTION

EMU Technologies ID Reader aligns and reads the Identification tag on a 150mm or 200mm wafer.

The system uses a Cognex 1741 Camera and is able to read Lasermarks or Datamatrix Tags on the active and rear faces of a wafer. Wafers are aligned using our patented batch alignment system.

Carrier are mapped prior to alignment & reading, checking for wafer presence cross and/or double slots.

The system can be connected to the host by SECS/GEM II through RS232 or Ethernet. Process recipes and maintenance can be accessed via a simple to use touchscreen interface.

The system provides true-ESD Protection for wafers and carriers.

The machine cycle time for reading a batch of 25 wafers is 2 minutes, including cassette mapping, batch alignment and reading each wafer in the Lot.

## FACILITY REQUIREMENTS

100/240V AC - 50-60Hz - 1.2A

## SPECIFICATIONS

**Footprint:** 475x395x375mm (LxWxH)  
 (Tabletop)



## RECIF TECHNOLOGY

This tool has been designed under license from Recif Technologies using the same design principles, materials and kinematics as were used in the original equipment and wafer fabs around the world.

SUPPLIERS TO THE SEMICONDUCTOR INDUSTRY

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